

## Supplementary Materials

# Ultra-sensitive flexible pressure sensor based on microstructured electrode

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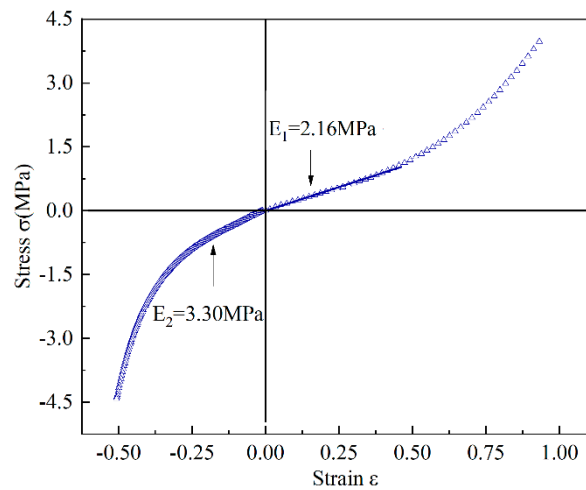


Figure S1 The measurement of stress-strain curve for 10:1 PDMS

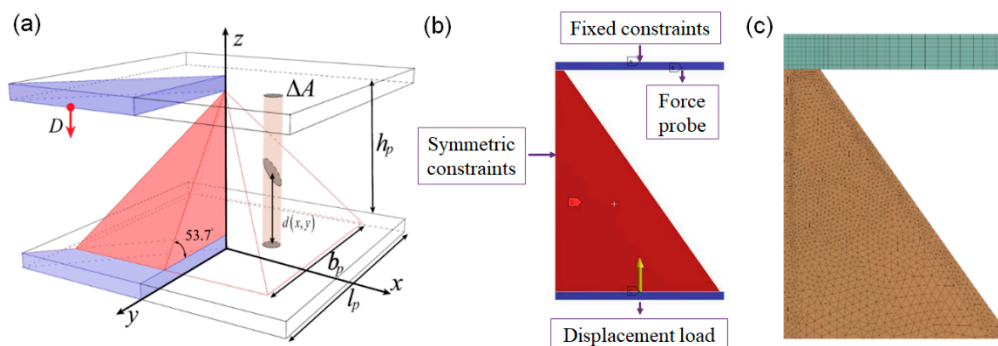


Figure S2 (a) Single pyramid microstructure capacitive sensor, (b) boundary conditions of the model, (c) the nonlinear mesh grid at the tip of the pyramid. Where  $b_p$  is the width of the micro-pyramid,  $l_p$  is the side length of the square electrode plate,  $h_p$  is the electrode distance.